

Amendt of
12/11/03

Amendments to the Specification

Please replace the title with the following new title.

~~Semiconductor Processing Methods of Forming Photoresist over Silicon Nitride Materials, and Semiconductor Wafer Assemblies Comprising Photoresist over Silicon Nitride Materials~~

At page 1, please replace the Related Patent Data section with the following new Related Patent Data Section.

RELATED PATENT DATA

This application resulted from a continuation application from U.S. Patent
Application Serial No. 09/995,372, filed on November 26, 2001 ^{Pat. 6,693,345} which resulted from a
continuation application of U.S. Patent Application Serial No. 09/724,749, which was filed
on November 27, 2000, now U.S. Patent No. 6,417,559 which is a divisional application of
U.S. Patent Application Serial No. 09/457,093, which was filed December 7, 1999, now
U.S. Patent No. 6,323,139 This application which is a continuation-in-part of U.S. Patent
Application Serial No. 09/057,155, filed April 7, 1998, now U.S. Patent No. 6,300,253; and
a continuation-in-part of U.S. Patent Application Serial No. 09/295,642, filed April 20, 1999
now U.S. Patent No. 6,297,171; which is a continuation of U.S. Patent Application Serial
No. 08/567,090, now U.S. Patent No. 5,926,739.

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